

FIG. 1A

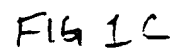
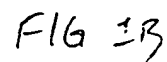


Fig. 2

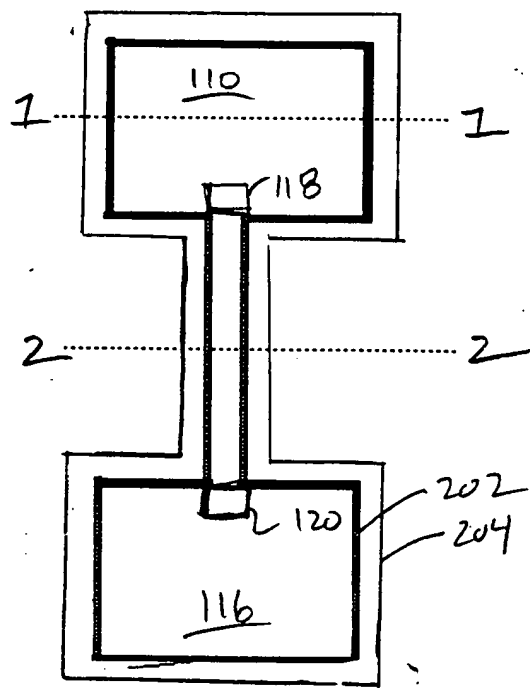


FIG 2A

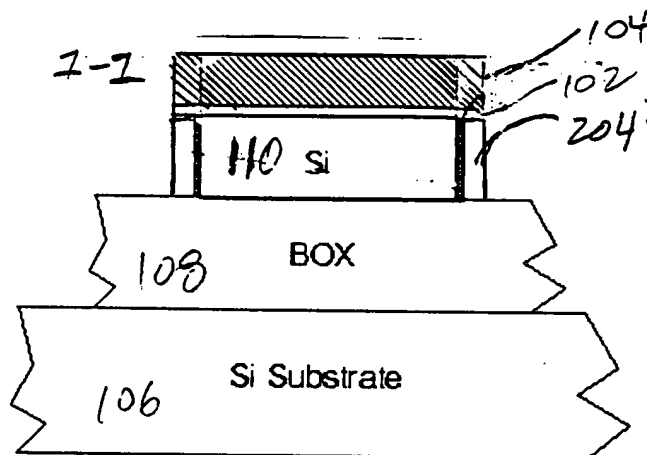


FIG 2B

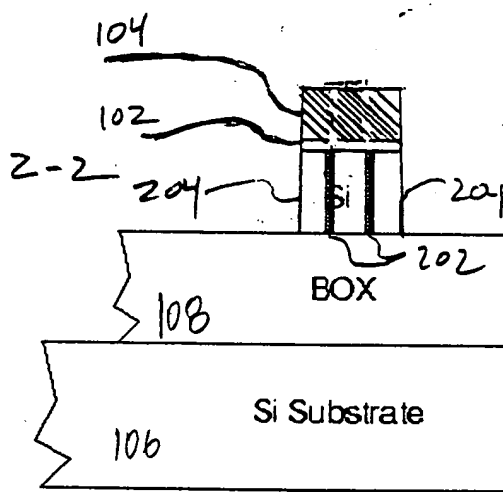


FIG. 2C

000001-000000

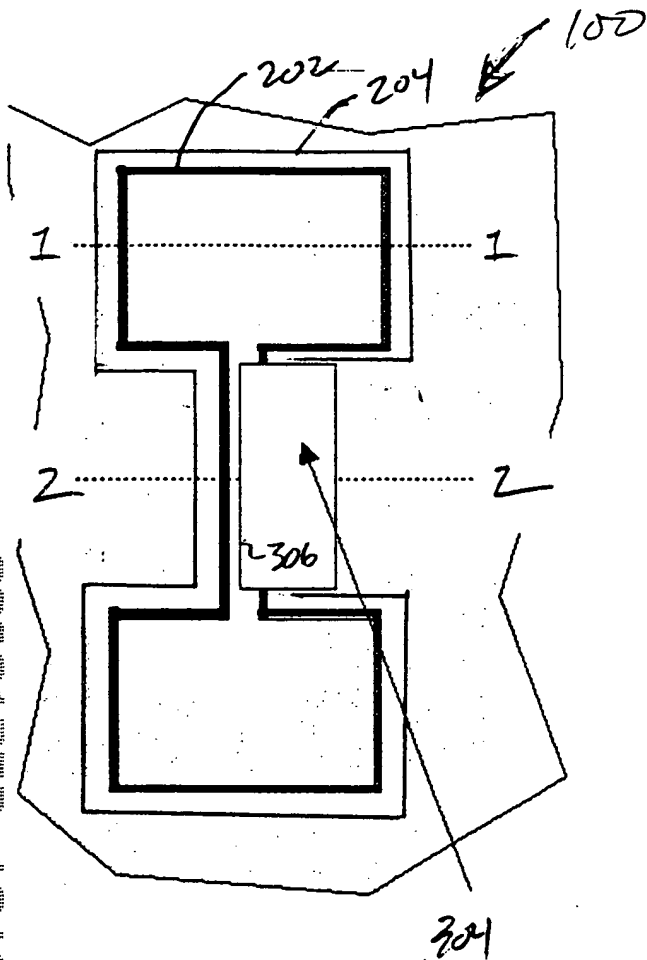


FIG 3A

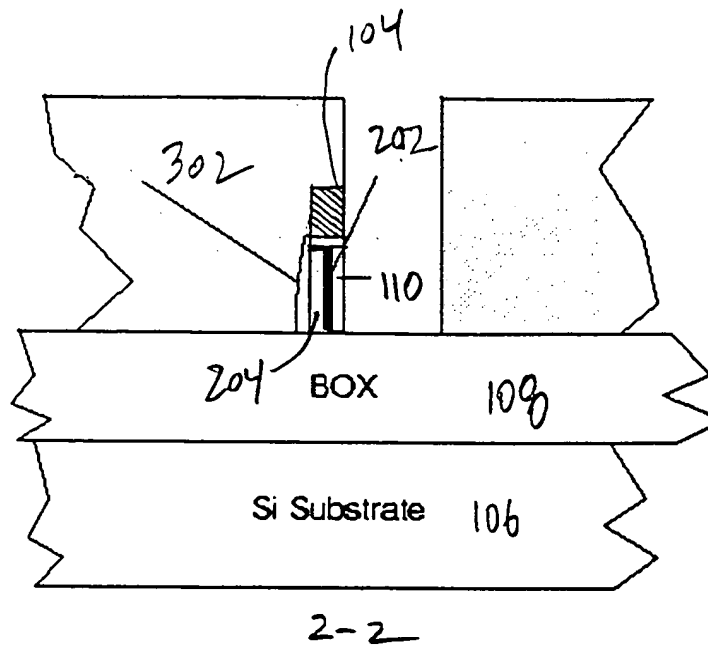


FIG 3B

FIG. 3

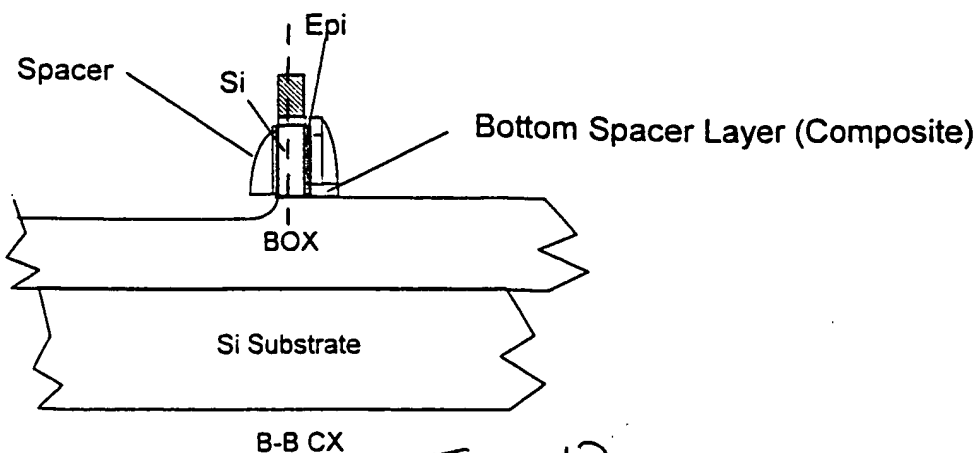


FIG. 12

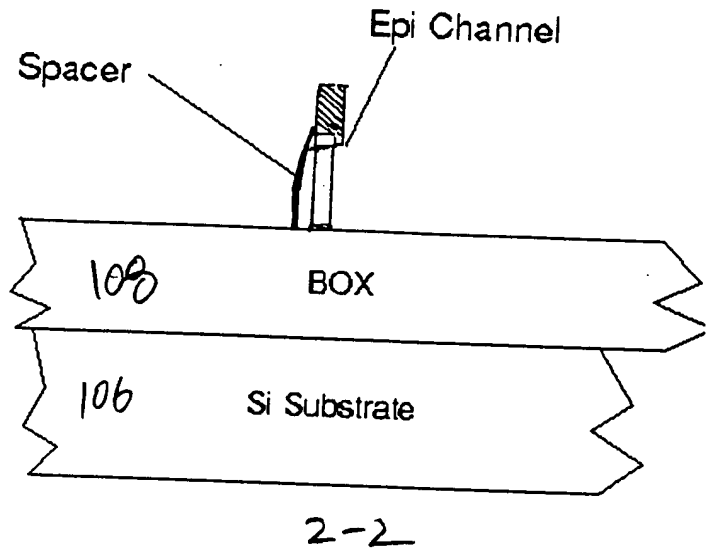
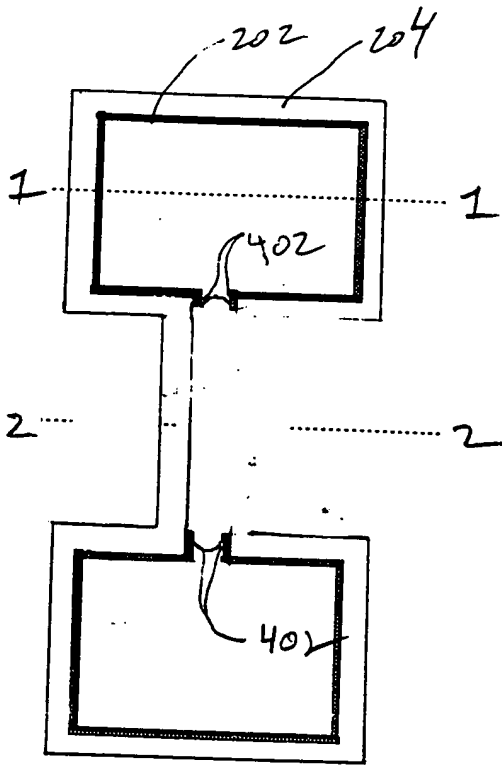


FIG. 4

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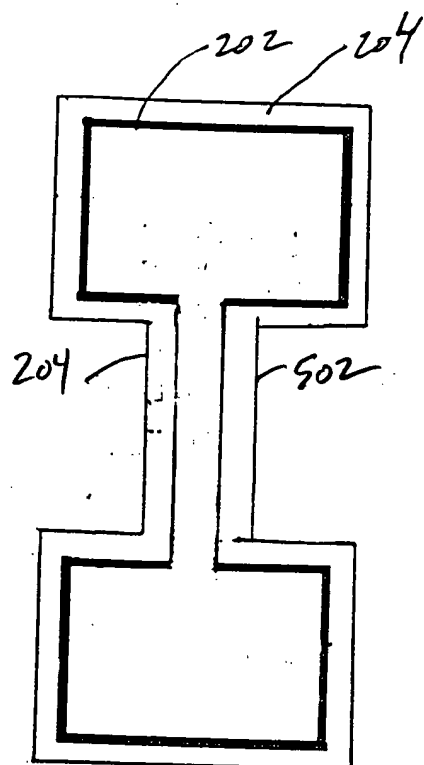


FIG 5



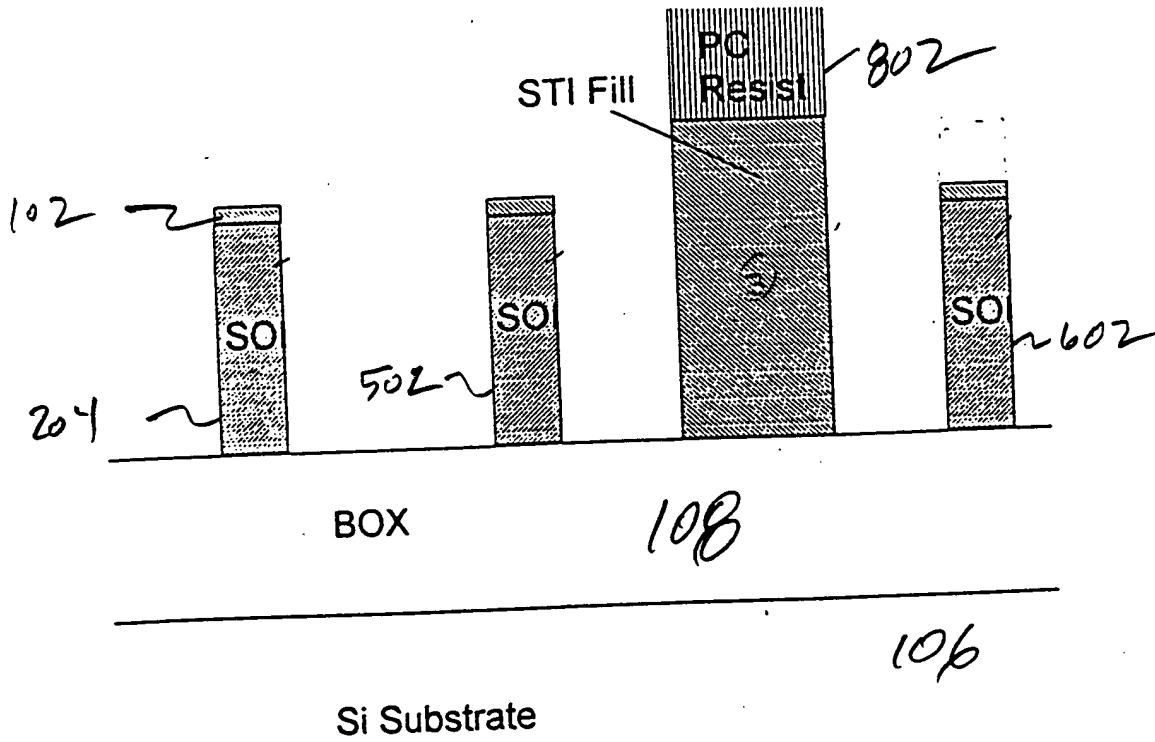


Fig 8A

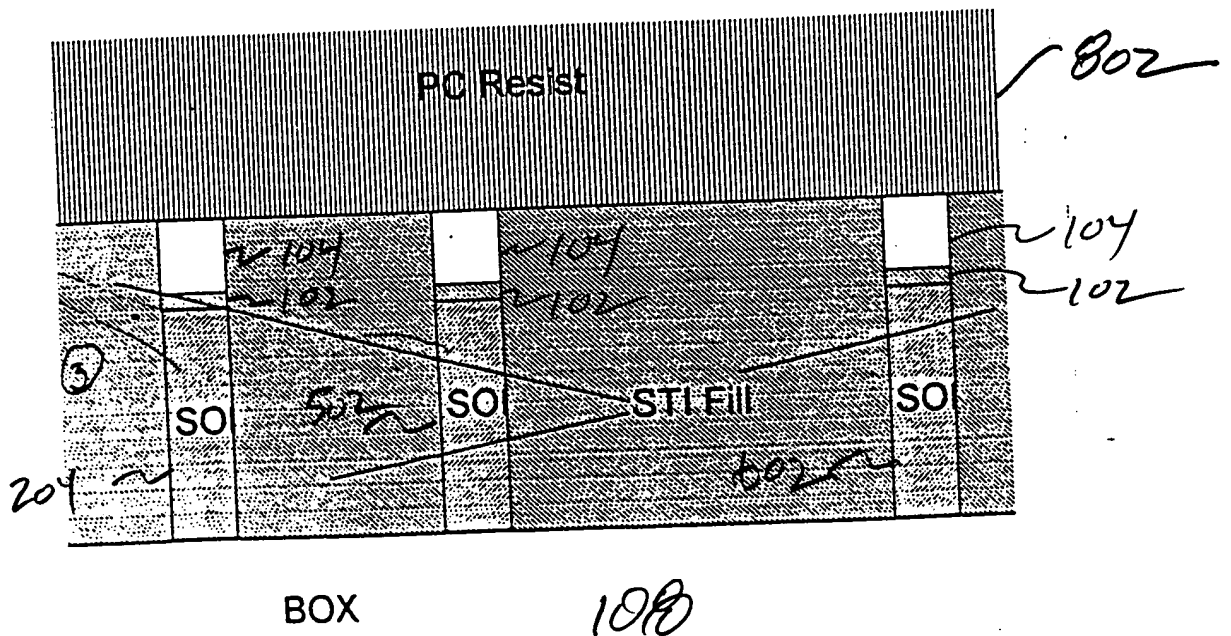
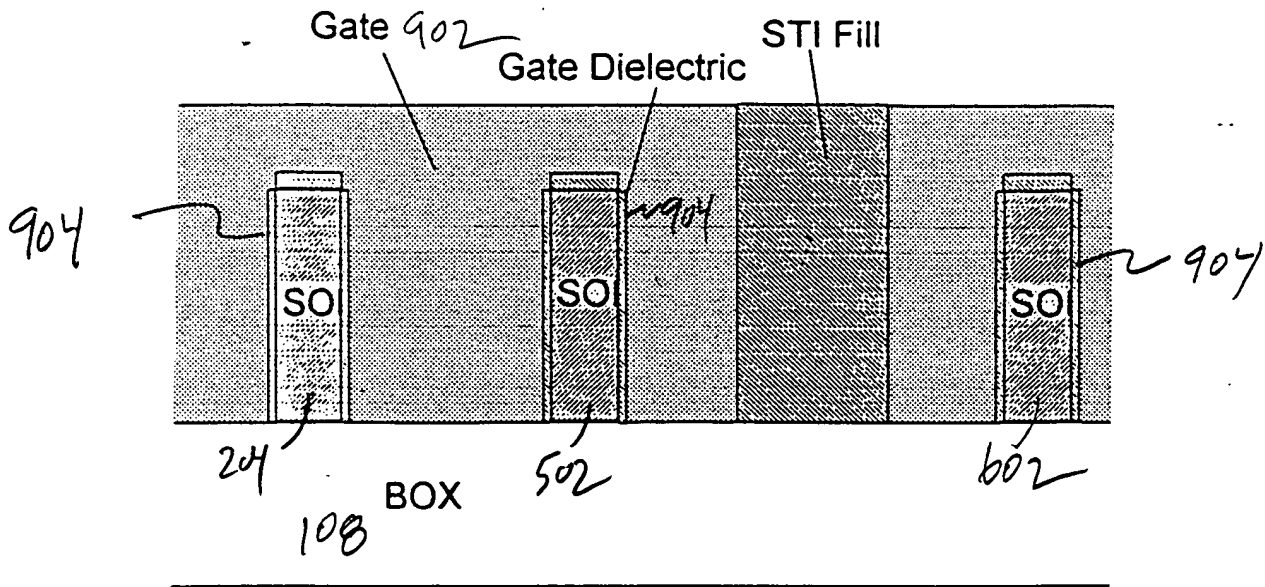


Fig 8B



Si Substrate

Fig. 9A

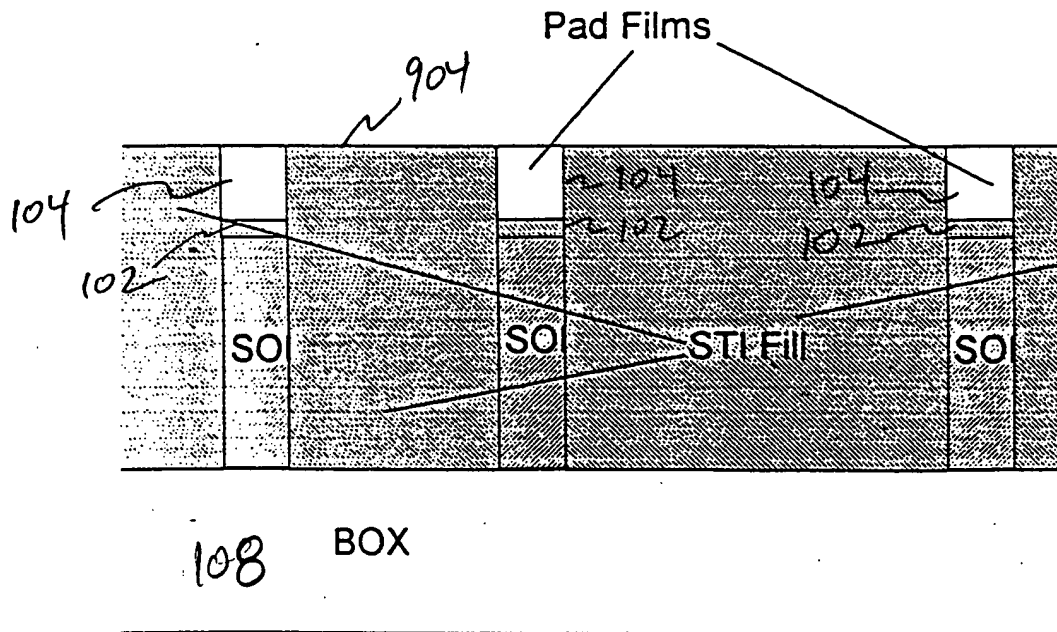
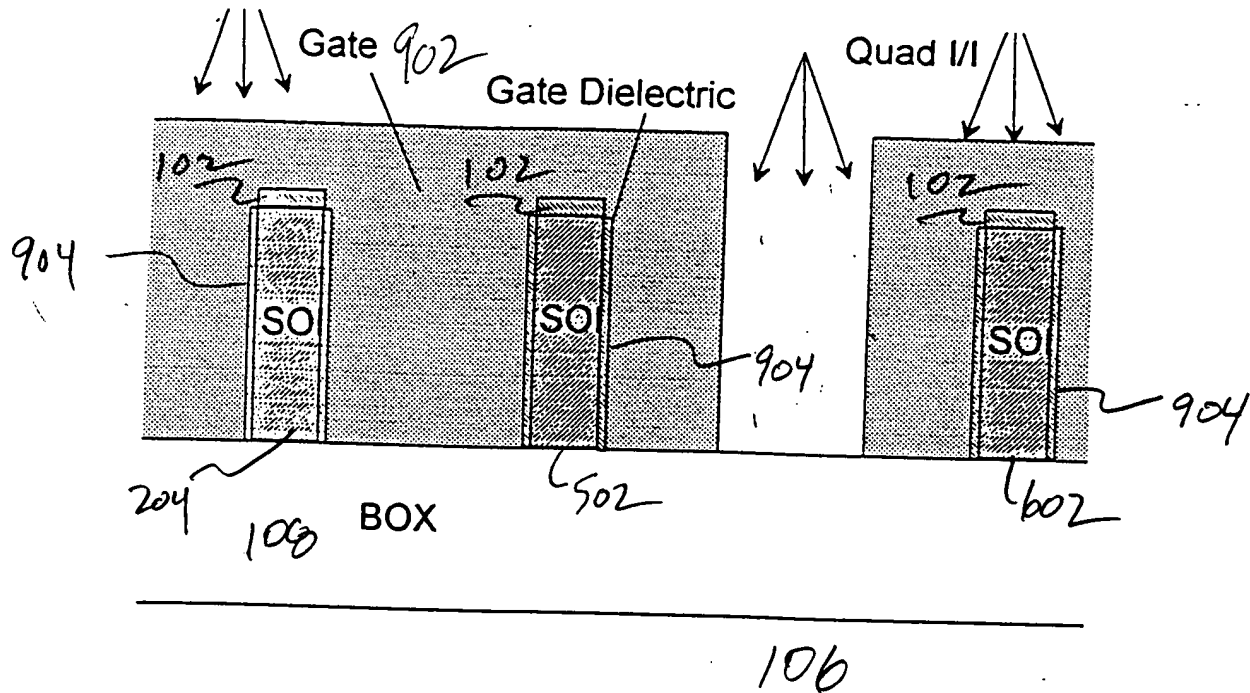


Fig. 9B



Si Substrate
Fig 10A

Extension Implant - Done w/ angle relative to substrate and repeated 4 times at cardinal directions relative to notch.

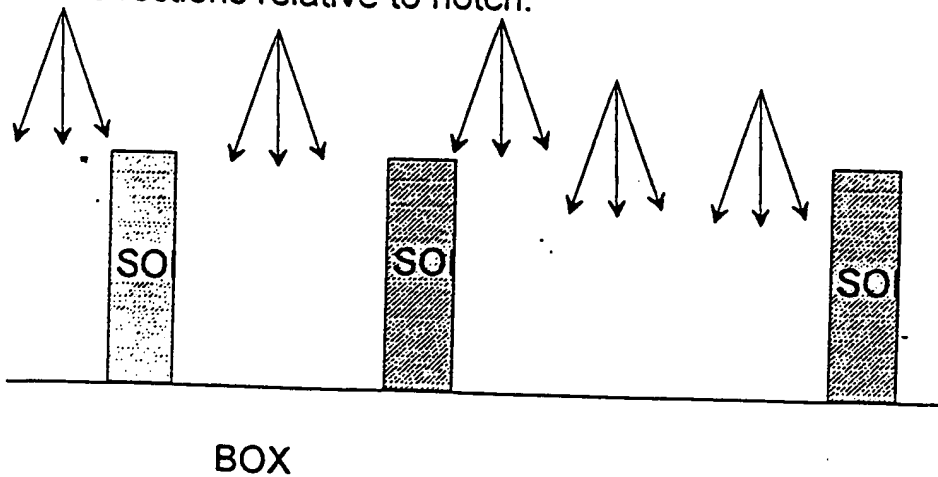


Fig 10B

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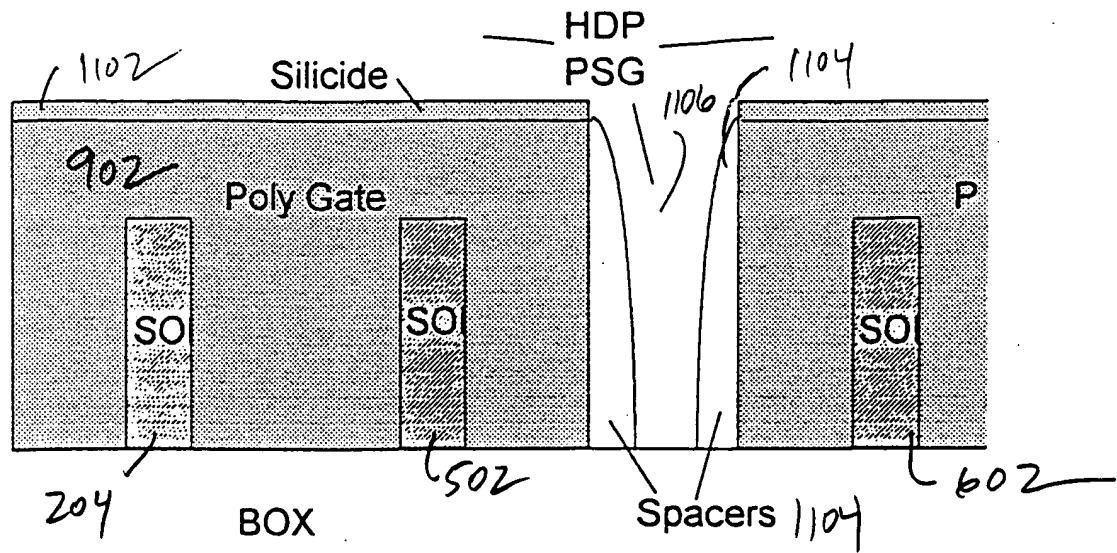


Fig 11A

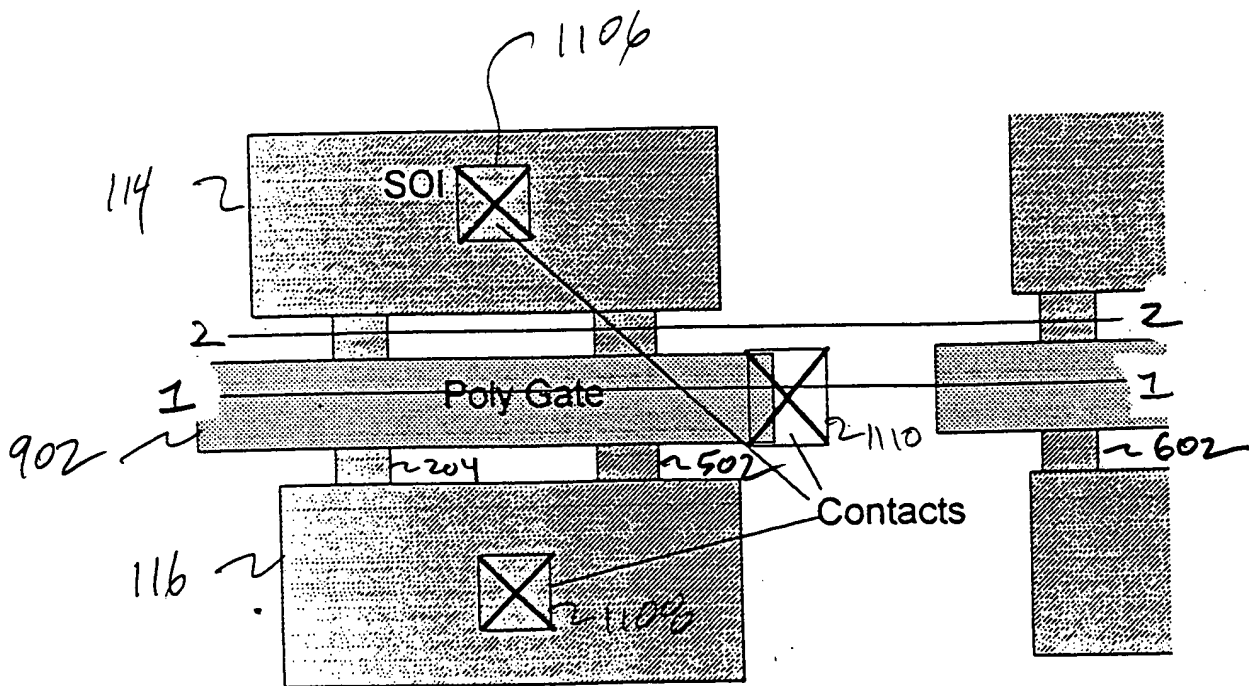


Fig 11B